

L Number	Hits	Search Text	DB	Time stamp
-	4	"200012465"	EPO; JPO; DERWENT	2003/11/04 10:06
-	11	"12465"	EPO; JPO; DERWENT	2003/11/03 13:00
-	0	"P200012465"	EPO; JPO; DERWENT	2003/11/03 13:01
-	2	"09237927"	EPO; JPO; DERWENT	2003/11/03 13:01
-	2	5866471.pn.	EPO; JPO; DERWENT	2003/11/04 08:28
-	1	5866471.pn.	USPAT; US-PGPUB	2003/11/04 08:28
-	30	(Furusawa.in. or Miyashita.in. or Yudasaka.in. or Shimoda.in. or Yokoyama.in. or Matsuki.in. or Takeuchi.in. or JSR.as. or (Seiko adj Epson).as.) and ((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3)) and ((ring adj silane) or (cyclic adj silane) or cyclosilane or cyclopentasilane or Si5H10 or "Si.sub.5 H.sub.10" or "Si.sub.5H.sub.10" or (cyclo adj pentasilane) or (cyclo adj penta adj silane) or silylcyclopentasilane or Si6H12 or "Si.sub.6H.sub.12" or "Si.sub.6 H.sub.12" or (silyl near2 cyclopentasilane))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/04 11:11
-	19	"59015"	EPO; JPO; DERWENT; IBM_TDB	2003/11/04 10:29
-	2	"200059015"	EPO; JPO; DERWENT; IBM_TDB	2003/11/04 10:29
-	2	"200059044"	EPO; JPO; DERWENT; IBM_TDB	2003/11/04 11:08
-	1420	(427/552,553,555,558).CCLS.	USPAT; US-PGPUB	2003/11/04 11:09
-	1056	(427/226).CCLS.	USPAT; US-PGPUB	2003/11/04 11:09
-	2229	((427/248.1,255.18,255.23) or (438/503,507)).CCLS.	USPAT; US-PGPUB	2003/11/04 11:09
-	2859	(427/258,259,261,264,265,270,271).CCLS.	USPAT; US-PGPUB	2003/11/04 11:10
-	417	(423/348,349).CCLS.	USPAT; US-PGPUB	2003/11/04 11:10
-	519	(117/88,95).CCLS.	USPAT; US-PGPUB	2003/11/04 11:10
-	8126	((427/552,553,555,558).CCLS.) ((427/226).CCLS.) ((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) ((427/258,259,261,264,265,270,271).CCLS.) ((423/348,349).CCLS.) ((117/88,95).CCLS.)	USPAT; US-PGPUB	2003/11/04 11:11
-	14	((427/552,553,555,558).CCLS.) ((427/226).CCLS.) ((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) ((427/258,259,261,264,265,270,271).CCLS.) ((423/348,349).CCLS.) ((117/88,95).CCLS.) and ((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3)) and ((ring adj silane) or (cyclic adj silane) or cyclosilane or cyclopentasilane or Si5H10 or "Si.sub.5 H.sub.10" or "Si.sub.5H.sub.10" or (cyclo adj pentasilane) or (cyclo adj penta adj silane) or silylcyclopentasilane or Si6H12 or "Si.sub.6H.sub.12" or "Si.sub.6 H.sub.12" or (silyl near2 cyclopentasilane))	USPAT; US-PGPUB	2003/11/04 13:46

-	3	((427/552,553,555,558).CCLS.) or ((427/258,259,261,264,265,270,271).CCLS.)) and ((ring adj silane) or (cyclic adj silane) or cyclosilane or cyclopentasilane or Si5H10 or "Si.sub.5 H.sub.10" or "Si.sub.5H.sub.10" or (cyclo adj pentasilane) or (cyclo adj penta adj silane) or silylcyclopentasilane or Si6H12 or "Si.sub.6H.sub.12" or "Si.sub.6 H.sub.12" or (silyl near2 cyclopentasilane))	USPAT; US-PGPUB	2003/11/04 11:19
-	32	((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) and ((427/258,259,261,264,265,270,271).CCLS.))	USPAT; US-PGPUB	2003/11/04 11:22
-	15	((427/552,553,555,558).CCLS.) ((427/226).CCLS.) ((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) ((427/258,259,261,264,265,270,271).CCLS.) ((423/348,349).CCLS.) ((117/88,95).CCLS.)) and ((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD or vaporiz\$5)) with (select\$7 or pattern\$3 or nonuniform or (non adj uniform))) and ((monolayer or (mono adj layer) or fluoroalkyl or fluorine or SAM or (self adj assembl\$3) or fluoro\$12) with (mask\$3 or inactiv\$5 or (in adj activ\$5) or deactiv\$5 or (de adj activ\$5)))	USPAT; US-PGPUB	2003/11/04 11:30
-	694	((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD or vaporiz\$5)) with (select\$7 or pattern\$3 or nonuniform or (non adj uniform))) and ((monolayer or (mono adj layer) or fluoroalkyl or fluorine or SAM or (self adj assembl\$3) or fluoro\$12) with (mask\$3 or inactiv\$5 or (in adj activ\$5) or deactiv\$5 or (de adj activ\$5)))	USPAT; US-PGPUB	2003/11/04 11:32
-	59	((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD or vaporiz\$5)) with (select\$7 or pattern\$3 or nonuniform or (non adj uniform))) and ((monolayer or (mono adj layer) or SAM or (self adj assembl\$3)) with (mask\$3 or inactiv\$5 or (in adj activ\$5) or deactiv\$5 or (de adj activ\$5)))	USPAT; US-PGPUB	2003/11/04 12:54
-	53	((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD or vaporiz\$5)) with (select\$7 or pattern\$3 or nonuniform or (non adj uniform))) and ((monolayer or (mono adj layer) or SAM or (self adj assembl\$3)) with (mask\$3 or inactiv\$5 or (in adj activ\$5) or deactiv\$5 or (de adj activ\$5)))) not (((427/552,553,555,558).CCLS.) ((427/226).CCLS.) ((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) ((427/258,259,261,264,265,270,271).CCLS.) ((423/348,349).CCLS.) ((117/88,95).CCLS.)) and ((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD or vaporiz\$5)) with (select\$7 or pattern\$3 or nonuniform or (non adj uniform))) and ((monolayer or (mono adj layer) or fluoroalkyl or fluorine or SAM or (self adj assembl\$3) or fluoro\$12) with (mask\$3 or inactiv\$5 or (in adj activ\$5) or deactiv\$5 or (de adj activ\$5))))	USPAT; US-PGPUB	2003/11/04 11:33

-	2	((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD or vaporiz\$5)) with (select\$7 or pattern\$3 or nonuniform or (non adj uniform))) and ((monolayer or (mono adj layer) or SAM or (self adj assembl\$3)) with (mask\$3 or inactiv\$5 or (in adj activ\$5) or deactiv\$5 or (de adj activ\$5)))	EPO; JPO; DERWENT; IBM_TDB	2003/11/04 11:39
-	7	((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD or vaporiz\$5))) and ((monolayer or (mono adj layer) or SAM or (self adj assembl\$3)) with (mask\$3 or inactiv\$5 or (in adj activ\$5) or deactiv\$5 or (de adj activ\$5) or pattern\$3))	EPO; JPO; DERWENT; IBM_TDB	2003/11/04 11:42
-	466	((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD or vaporiz\$5))) and ((monolayer or (mono adj layer) or SAM or (self adj assembl\$3)) with (mask\$3 or inactiv\$5 or (in adj activ\$5) or deactiv\$5 or (de adj activ\$5) or pattern\$3))	USPAT; US-PGPUB	2003/11/04 11:43
-	27	((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD or vaporiz\$5))) and ((monolayer or (mono adj layer) or SAM or (self adj assembl\$3)) with (mask\$3 or inactiv\$5 or (in adj activ\$5) or deactiv\$5 or (de adj activ\$5) or pattern\$3))) and ((427/552,553,555,558).CCLS.) ((427/226).CCLS.) ((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) ((427/258,259,261,264,265,270,271).CCLS.) ((423/348,349).CCLS.) ((117/88,95).CCLS.))	USPAT; US-PGPUB	2003/11/04 11:53
-	1	((tridecafluoro near3 triethoxysilane) or FAS13 or ("FAS 13")) same (monolayer or (mono adj layer) or SAM or (self adj assembl\$5) or pattern or mask\$3 or inactiv\$5 or (in adj activ\$5) or (de adj activ\$5) or deactiv\$5)	USPAT; US-PGPUB	2003/11/04 11:57
-	1	((tridecafluoro near5 triethoxysilane) or FAS13 or ("FAS 13")) same (monolayer or (mono adj layer) or SAM or (self adj assembl\$5) or pattern or mask\$3 or inactiv\$5 or (in adj activ\$5) or (de adj activ\$5) or deactiv\$5)	USPAT; US-PGPUB	2003/11/04 11:57
-	60	((tridecafluoro near5 triethoxysilane) or FAS13 or ("FAS 13")) and (monolayer or (mono adj layer) or SAM or (self adj assembl\$5) or pattern or mask\$3 or inactiv\$5 or (in adj activ\$5) or (de adj activ\$5) or deactiv\$5)	USPAT; US-PGPUB	2003/11/04 12:07
-	4	((tridecafluoro near5 triethoxysilane) or FAS13 or ("FAS 13")) and (monolayer or (mono adj layer) or SAM or (self adj assembl\$5) or pattern or mask\$3 or inactiv\$5 or (in adj activ\$5) or (de adj activ\$5) or deactiv\$5)) and ((427/552,553,555,558).CCLS.) ((427/226).CCLS.) ((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) ((427/258,259,261,264,265,270,271).CCLS.) ((423/348,349).CCLS.) ((117/88,95).CCLS.))	USPAT; US-PGPUB	2003/11/04 11:58

-	56	((tridecafluoro near5 triethoxysilane) or FAS13 or ("FAS 13")) and (monolayer or (mono adj layer) or SAM or (self adj assembl\$5) or pattern or mask\$3 or inactiv\$5 or (in adj activ\$5) or (de adj activ\$5) or deactiv\$5)) not (((tridecafluoro near5 triethoxysilane) or FAS13 or ("FAS 13")) and (monolayer or (mono adj layer) or SAM or (self adj assembl\$5) or pattern or mask\$3 or inactiv\$5 or (in adj activ\$5) or (de adj activ\$5) or deactiv\$5)) and (((427/552,553,555,558).CCLS.) ((427/226).CCLS.) (((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) ((427/258,259,261,264,265,270,271).CCLS.) ((423/348,349).CCLS.) ((117/88,95).CCLS.)))	USPAT; US-PGPUB	2003/11/04 12:01
-	0	((tridecafluoro near5 triethoxysilane) or FAS13 or ("FAS 13")) and (monolayer or (mono adj layer) or SAM or (self adj assembl\$5) or pattern or mask\$3 or inactiv\$5 or (in adj activ\$5) or (de adj activ\$5) or deactiv\$5)	EPO; JPO; DERWENT; IBM_TDB	2003/11/04 12:49
-	4	Meeks.xp,xa. and (self adj assemb\$8)	USPAT;	2003/11/04 12:51
-	46692	((Si or silicon) with (coat\$3 or film or layer or deposit\$3 or \$4CVD) with (pattern\$3 or nonuniform\$3 or (non adj uniform\$3) or mask\$3))	US-PGPUB USPAT; US-PGPUB	2003/11/04 12:59
-	573	((Si or silicon) with (coat\$3 or film or layer or deposit\$3 or \$4CVD) with (pattern\$3 or nonuniform\$3 or (non adj uniform\$3) or mask\$3))) and (((427/552,553,555,558).CCLS.) ((427/226).CCLS.) (((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) ((427/258,259,261,264,265,270,271).CCLS.) ((423/348,349).CCLS.) ((117/88,95).CCLS.)))	USPAT; US-PGPUB	2003/11/04 12:54
-	422	((Si or silicon) with (coat\$3 or film or layer or deposit\$3 or \$4CVD) with (pattern\$3 or nonuniform\$3 or (non adj uniform\$3) or mask\$3))) and (((427/552,553,555,558).CCLS.) ((427/226).CCLS.) (((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) ((427/258,259,261,264,265,270,271).CCLS.) ((423/348,349).CCLS.) ((117/88,95).CCLS.))) and ((monolayer or (mono adj layer) or SAM or (self adj assembl\$3)) or (mask\$3 or inactiv\$5 or (in adj activ\$5) or deactiv\$5 or (de adj activ\$5)))	USPAT; US-PGPUB	2003/11/04 13:52
-	31013	((Si or silicon) with (coat\$3 or film or layer or deposit\$3 or \$4CVD) with (pattern\$3 or nonuniform\$3 or (non adj uniform\$3) or mask\$3))) same ((monolayer or (mono adj layer) or SAM or (self adj assembl\$3)) or (mask\$3 or inactiv\$5 or (in adj activ\$5) or deactiv\$5 or (de adj activ\$5)))	USPAT; US-PGPUB	2003/11/04 12:57
-	398	((Si or silicon) with (coat\$3 or film or layer or deposit\$3 or \$4CVD) with (pattern\$3 or nonuniform\$3 or (non adj uniform\$3) or mask\$3))) same ((monolayer or (mono adj layer) or SAM or (self adj assembl\$3)) or (inactiv\$5 or (in adj activ\$5) or deactiv\$5 or (de adj activ\$5)))	USPAT; US-PGPUB	2003/11/04 12:57

-	5	(((Si or silicon) with (coat\$3 or film or layer or deposit\$3 or \$4CVD) with (pattern\$3 or nonuniform\$3 or (non adj uniform\$3) or mask\$3))) same ((monolayer or (mono adj layer) or SAM or (self adj assembl\$3)) or (inactiv\$5 or (in adj activ\$5) or deactiv\$5 or (de adj activ\$5)))) and ((427/552,553,555,558).CCLS.) ((427/226).CCLS.) ((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) ((427/258,259,261,264,265,270,271).CCLS.) ((423/348,349).CCLS.) ((117/88,95).CCLS.))	USPAT; US-PGPUB	2003/11/04 12:57
-	13228	((Si or silicon) adj (coat\$3 or film or layer or deposit\$3 or \$4CVD) with (pattern\$3 or nonuniform\$3 or (non adj uniform\$3) or selecti\$6))	USPAT; US-PGPUB	2003/11/04 13:02
-	170	(((Si or silicon) adj (coat\$3 or film or layer or deposit\$3 or \$4CVD) with (pattern\$3 or nonuniform\$3 or (non adj uniform\$3) or selecti\$6))) and ((427/552,553,555,558).CCLS.) ((427/226).CCLS.) ((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) ((427/258,259,261,264,265,270,271).CCLS.) ((423/348,349).CCLS.) ((117/88,95).CCLS.))	USPAT; US-PGPUB	2003/11/04 13:01
-	1680	((Si or silicon) adj (coat\$3 or film or layer or deposit\$3 or \$4CVD) with (pattern\$3 or nonuniform\$3 or (non adj uniform\$3) or selecti\$6) with (\$4CVD or (vapor\$9)))	USPAT; US-PGPUB	2003/11/04 13:03
-	37	(((Si or silicon) adj (coat\$3 or film or layer or deposit\$3 or \$4CVD) with (pattern\$3 or nonuniform\$3 or (non adj uniform\$3) or selecti\$6) with (\$4CVD or (vapor\$9)))) and ((427/552,553,555,558).CCLS.) ((427/226).CCLS.) ((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) ((427/258,259,261,264,265,270,271).CCLS.) ((423/348,349).CCLS.) ((117/88,95).CCLS.))	USPAT; US-PGPUB	2003/11/04 13:08
-	589	(selective near2 (coat\$3 or deposit\$3 or \$4CVD) near2 (Si or silicon))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/04 13:14
-	20	((selective near2 (coat\$3 or deposit\$3 or \$4CVD) near2 (Si or silicon))) and (SAM or monolayer or (self adj assembl\$7) or (mono adj layer))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/04 13:32
-	106	(selective near2 (coat\$3 or deposit\$3 or \$4CVD) near2 (Si or silicon)) same pattern\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/04 13:30
-	103	((selective near2 (coat\$3 or deposit\$3 or \$4CVD) near2 (Si or silicon)) same pattern\$3) not ((selective near2 (coat\$3 or deposit\$3 or \$4CVD) near2 (Si or silicon))) and (SAM or monolayer or (self adj assembl\$7) or (mono adj layer)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/04 13:15
-	103	(selective near2 (coat\$3 or deposit\$3 or \$4CVD) near2 (Si or silicon))	EPO; JPO; DERWENT; IBM TDB	2003/11/04 13:32

-	29	((selective near2 (coat\$3 or deposit\$3 or \$4CVD) near2 (Si or silicon))) and (SAM or monolayer or (self adj assemb\$7) or (mono adj layer) or inactiv\$5 or mask\$3 or deactiv\$5 or (in adj activ\$5) or (de adj activ\$5))	EPO; JPO; DERWENT; IBM_TDB	2003/11/04 13:37
-	13	(selective near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD)) same (SAM or monolayer or (self adj assemb\$7) or (mono adj layer))	EPO; JPO; DERWENT; IBM_TDB	2003/11/04 13:38
-	109	(selective near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD)) same (SAM or monolayer or (self adj assemb\$7) or (mono adj layer))	USPAT; US-PGPUB	2003/11/04 13:45
-	7	"9707429"	EPO; JPO; DERWENT	2003/11/04 13:45
-	37	((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD)) and ((ring adj silane) or (cyclic adj silane) or cyclosilane or cyclopentasilane or Si5H10 or "Si.sub.5 H.sub.10" or "Si.sub.5H.sub.10" or (cyclo adj pentasilane) or (cyclo adj penta adj silane) or silylcyclopentasilane or Si6H12 or "Si.sub.6H.sub.12" or "Si.sub.6 H.sub.12" or (silyl near2 cyclopentasilane))	EPO; JPO; DERWENT; IBM_TDB	2003/11/04 13:50
-	141	((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD)) and ((ring adj silane) or (cyclic adj silane) or cyclosilane or cyclopentasilane or Si5H10 or "Si.sub.5 H.sub.10" or "Si.sub.5H.sub.10" or (cyclo adj pentasilane) or (cyclo adj penta adj silane) or silylcyclopentasilane or Si6H12 or "Si.sub.6H.sub.12" or "Si.sub.6 H.sub.12" or (silyl near2 cyclopentasilane))	USPAT; US-PGPUB	2003/11/04 14:01
-	14	((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD)) and ((ring adj silane) or (cyclic adj silane) or cyclosilane or cyclopentasilane or Si5H10 or "Si.sub.5 H.sub.10" or "Si.sub.5H.sub.10" or (cyclo adj pentasilane) or (cyclo adj penta adj silane) or silylcyclopentasilane or Si6H12 or "Si.sub.6H.sub.12" or "Si.sub.6 H.sub.12" or (silyl near2 cyclopentasilane))) and ((427/552,553,555,558).CCLS.) ((427/226).CCLS.) ((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) ((427/258,259,261,264,265,270,271).CCLS.) ((423/348,349).CCLS.) ((117/88,95).CCLS.))	USPAT; US-PGPUB	2003/11/04 13:52

-	127	(((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD)) and ((ring adj silane) or (cyclic adj silane) or cyclosilane or cyclopentasilane or Si5H10 or "Si.sub.5 H.sub.10" or "Si.sub.5H.sub.10" or (cyclo adj pentasilane) or (cyclo adj penta adj silane) or silylcyclopentasilane or Si6H12 or "Si.sub.6H.sub.12" or "Si.sub.6 H.sub.12" or (silyl near2 cyclopentasilane))) not (((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD)) and ((ring adj silane) or (cyclic adj silane) or cyclosilane or cyclopentasilane or Si5H10 or "Si.sub.5 H.sub.10" or "Si.sub.5H.sub.10" or (cyclo adj pentasilane) or (cyclo adj penta adj silane) or silylcyclopentasilane or Si6H12 or "Si.sub.6H.sub.12" or "Si.sub.6 H.sub.12" or (silyl near2 cyclopentasilane))) and (((427/552,553,555,558).CCLS.) ((427/226).CCLS.) (((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) ((427/258,259,261,264,265,270,271).CCLS.) ((423/348,349).CCLS.) ((117/88,95).CCLS.)))	USPAT; US-PGPUB	2003/11/04 13:52
-	2	(((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD)) and ((ring adj silane) or (cyclic adj silane) or cyclosilane or cyclopentasilane or Si5H10 or "Si.sub.5 H.sub.10" or "Si.sub.5H.sub.10" or (cyclo adj pentasilane) or (cyclo adj penta adj silane) or silylcyclopentasilane or Si6H12 or "Si.sub.6H.sub.12" or "Si.sub.6 H.sub.12" or (silyl near2 cyclopentasilane))) not (((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD)) and ((ring adj silane) or (cyclic adj silane) or cyclosilane or cyclopentasilane or Si5H10 or "Si.sub.5 H.sub.10" or "Si.sub.5H.sub.10" or (cyclo adj pentasilane) or (cyclo adj penta adj silane) or silylcyclopentasilane or Si6H12 or "Si.sub.6H.sub.12" or "Si.sub.6 H.sub.12" or (silyl near2 cyclopentasilane))) and (((427/552,553,555,558).CCLS.) ((427/226).CCLS.) (((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) ((427/258,259,261,264,265,270,271).CCLS.) ((423/348,349).CCLS.) ((117/88,95).CCLS.))) and ((monolayer or (mono adj layer) or SAM or (self adj assembl\$3)))	USPAT; US-PGPUB	2003/11/04 13:54

-	125	<p>(((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD)) and ((ring adj silane) or (cyclic adj silane) or cyclosilane or cyclopentasilane or Si5H10 or "Si.sub.5 H.sub.10" or "Si.sub.5H.sub.10" or (cyclo adj pentasilane) or (cyclo adj penta adj silane) or silylcyclopentasilane or Si6H12 or "Si.sub.6H.sub.12" or "Si.sub.6 H.sub.12" or (silyl near2 cyclopentasilane))) not (((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD)) and ((ring adj silane) or (cyclic adj silane) or cyclosilane or cyclopentasilane or Si5H10 or "Si.sub.5 H.sub.10" or "Si.sub.5H.sub.10" or (cyclo adj pentasilane) or (cyclo adj penta adj silane) or silylcyclopentasilane or Si6H12 or "Si.sub.6H.sub.12" or "Si.sub.6 H.sub.12" or (silyl near2 cyclopentasilane))) and (((427/552,553,555,558).CCLS.) ((427/226).CCLS.) (((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) ((427/258,259,261,264,265,270,271).CCLS.) ((423/348,349).CCLS.) ((117/88,95).CCLS.)))) not (((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD)) and ((ring adj silane) or (cyclic adj silane) or cyclosilane or cyclopentasilane or Si5H10 or "Si.sub.5 H.sub.10" or "Si.sub.5H.sub.10" or (cyclo adj pentasilane) or (cyclo adj penta adj silane) or silylcyclopentasilane or Si6H12 or "Si.sub.6H.sub.12" or "Si.sub.6 H.sub.12" or (silyl near2 cyclopentasilane))) not (((silicon or Si) near2 (coat\$3 or film or layer or deposit\$3 or \$4CVD)) and ((ring adj silane) or (cyclic adj silane) or cyclosilane or cyclopentasilane or Si5H10 or "Si.sub.5 H.sub.10" or "Si.sub.5H.sub.10" or (cyclo adj pentasilane) or (cyclo adj penta adj silane) or silylcyclopentasilane or Si6H12 or "Si.sub.6H.sub.12" or "Si.sub.6 H.sub.12" or (silyl near2 cyclopentasilane))) and (((427/552,553,555,558).CCLS.) ((427/226).CCLS.) (((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) ((427/258,259,261,264,265,270,271).CCLS.) ((423/348,349).CCLS.) ((117/88,95).CCLS.)))) and ((monolayer or mono adj layer) or SAM or (self adj assembl\$3))))</p>	USPAT; US-PGPUB	2003/11/04 13:54
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-	11	((silicon or Si) near4 (coat\$3 or film or layer or deposit\$3 or \$4CVD)) and ((ring adj silane) or (cyclic adj silane) or cyclosilane or cyclopentasilane or Si5H10 or "Si.sub.5 H.sub.10" or "Si.sub.5H.sub.10" or (cyclo adj pentasilane) or (cyclo adj penta adj silane) or silylcyclopentasilane or Si6H12 or "Si.sub.6H.sub.12" or "Si.sub.6 H.sub.12" or (silyl near2 cyclopentasilane)) and (ink adj jet\$4 or inkjet\$4 or (bubble adj jet\$4) or bubblejet\$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/04 14:03
-	1	((ring adj silane) or (cyclic adj silane) or cyclosilane or cyclopentasilane or Si5H10 or "Si.sub.5 H.sub.10" or "Si.sub.5H.sub.10" or (cyclo adj pentasilane) or (cyclo adj penta adj silane) or silylcyclopentasilane or Si6H12 or "Si.sub.6H.sub.12" or "Si.sub.6 H.sub.12" or (silyl near2 cyclopentasilane)) same (ink adj jet\$4 or inkjet\$4 or (bubble adj jet\$4) or bubblejet\$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/04 14:21
-	2	6527847.pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/04 14:13
-	401	(\$4CVD or (vapor adj deposit\$3)) same ((gas or inert or nitrogen or N2 or "N.sub.2") with parallel with (crucible or source or surface or vaporizer or blow\$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/04 14:29
-	28	(((\$4CVD or (vapor adj deposit\$3)) same ((gas or inert or nitrogen or N2 or "N.sub.2") with parallel with (crucible or source or surface or vaporizer or blow\$3))) and (((427/552,553,555,558).CCLS.) ((427/226).CCLS.) (((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) ((427/258,259,261,264,265,270,271).CCLS.) ((423/348,349).CCLS.) ((117/88,95).CCLS.)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/04 14:24
-	67	(\$4CVD or (vapor adj deposit\$3)) same (((inert or nonreactive or (non adj reactive) or noble) near2 gas\$4) or nitrogen or N2 or "N.sub.2" or hydrogen or H2 or "H.sub.2") with parallel with (crucible or source or surface or vaporizer or blow\$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/04 14:31
-	66	(((\$4CVD or (vapor adj deposit\$3)) same (((inert or nonreactive or (non adj reactive) or noble) near2 gas\$4) or nitrogen or N2 or "N.sub.2" or hydrogen or H2 or "H.sub.2") with parallel with (crucible or source or surface or vaporizer or blow\$3))) not (((\$4CVD or (vapor adj deposit\$3)) same ((gas or inert or nitrogen or N2 or "N.sub.2") with parallel with (crucible or source or surface or vaporizer or blow\$3))) and (((427/552,553,555,558).CCLS.) ((427/226).CCLS.) (((427/248.1,255.18,255.23) or (438/503,507)).CCLS.) ((427/258,259,261,264,265,270,271).CCLS.) ((423/348,349).CCLS.) ((117/88,95).CCLS.)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/04 14:31